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FIG. 1A

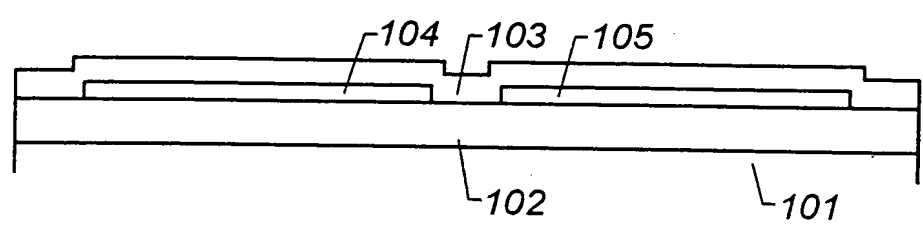


FIG. 1B

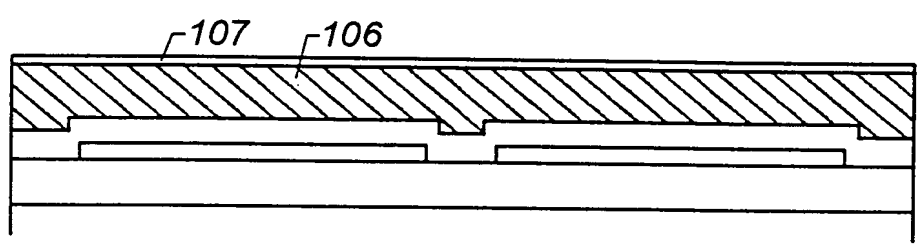


FIG. 1C

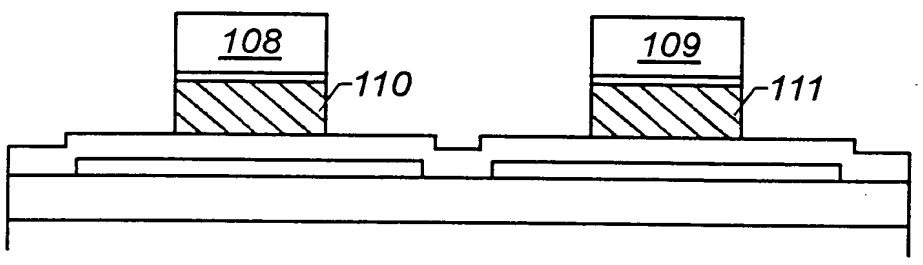


FIG. 1D

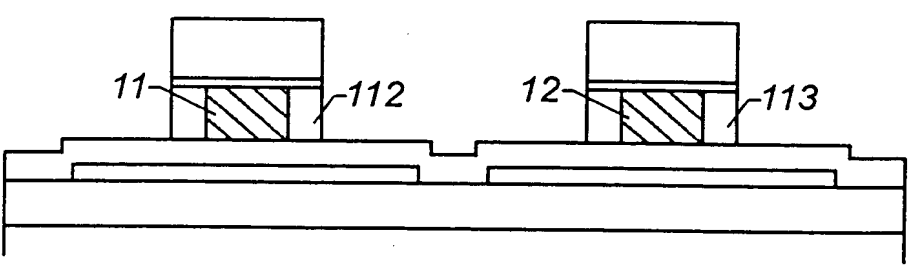
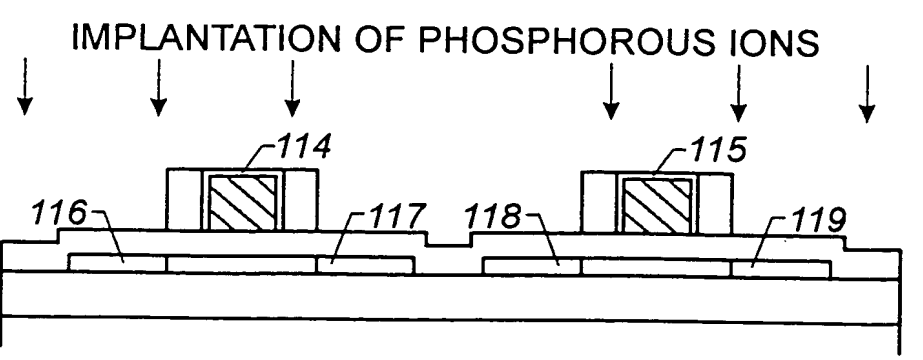


FIG. 1E



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FIG. 2A

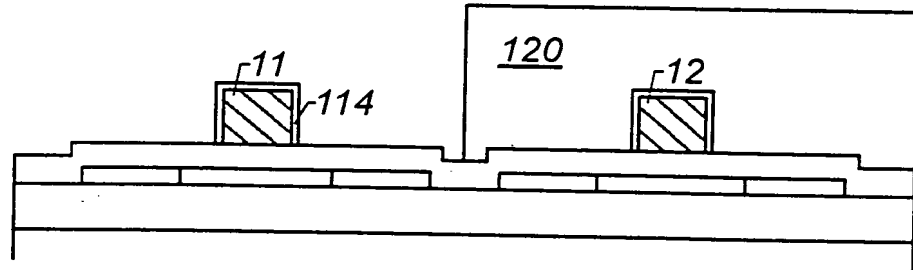


FIG. 2B

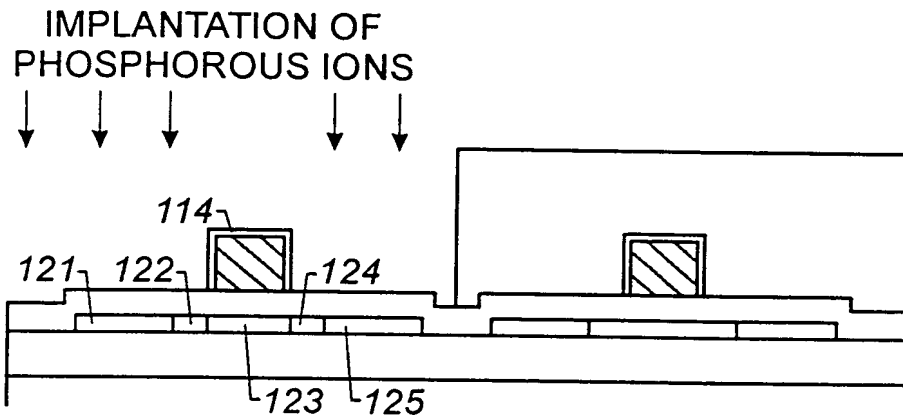


FIG. 2C

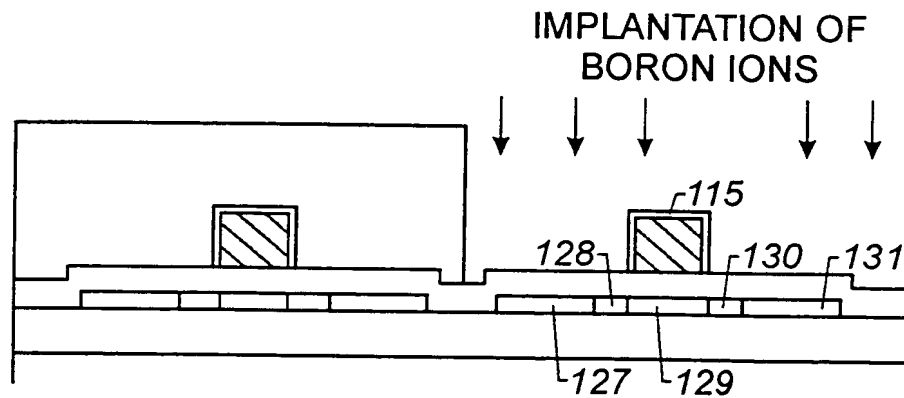


FIG. 2D

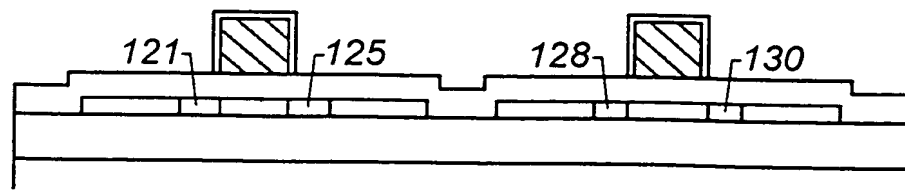


FIG. 3A

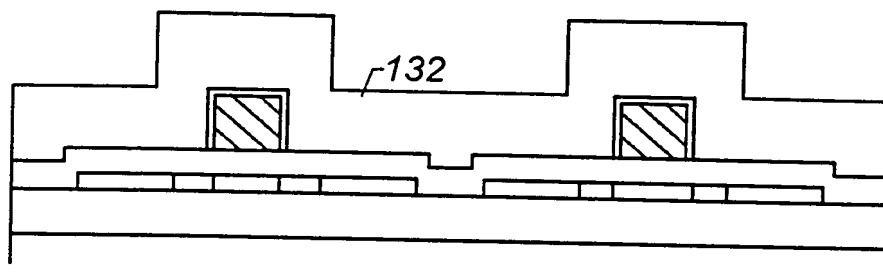


FIG. 3B

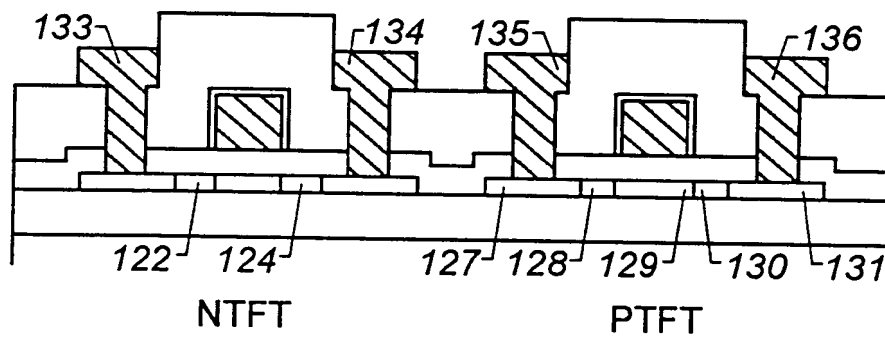


FIG. 4A
(PRIOR
ART)

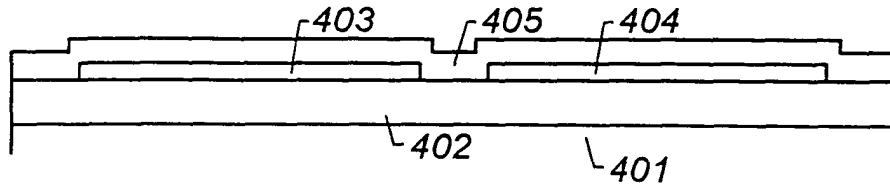


FIG. 4B
(PRIOR
ART)

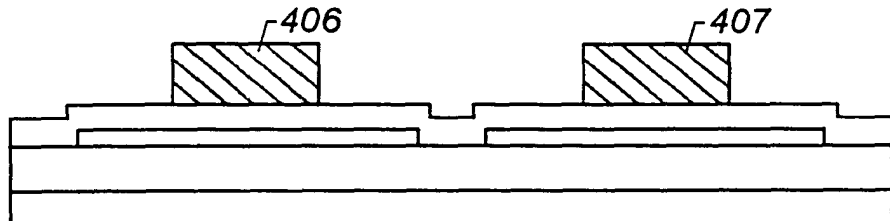


FIG. 4C
(PRIOR
ART)

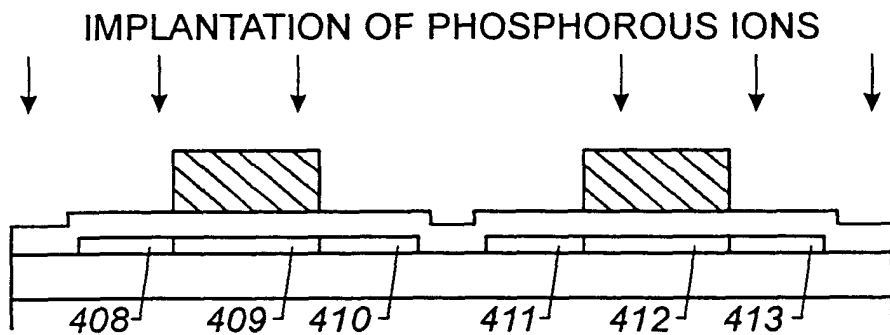
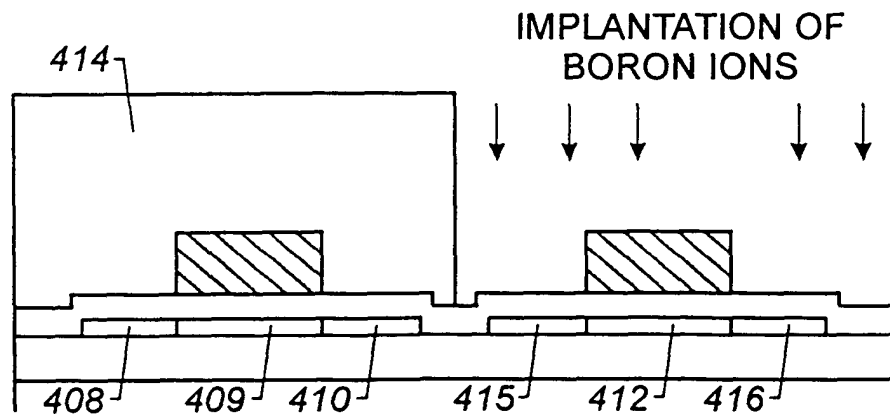


FIG. 4D
(PRIOR
ART)



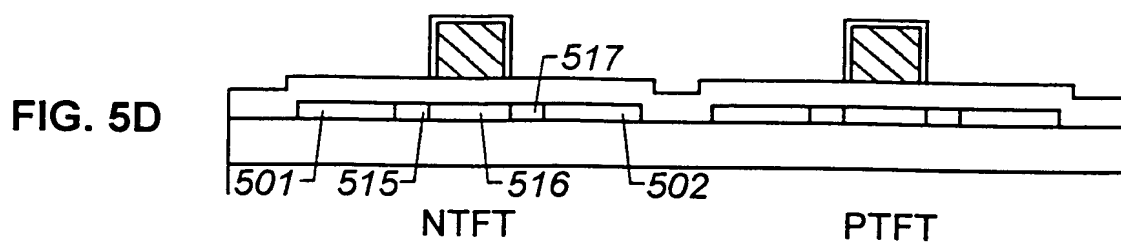
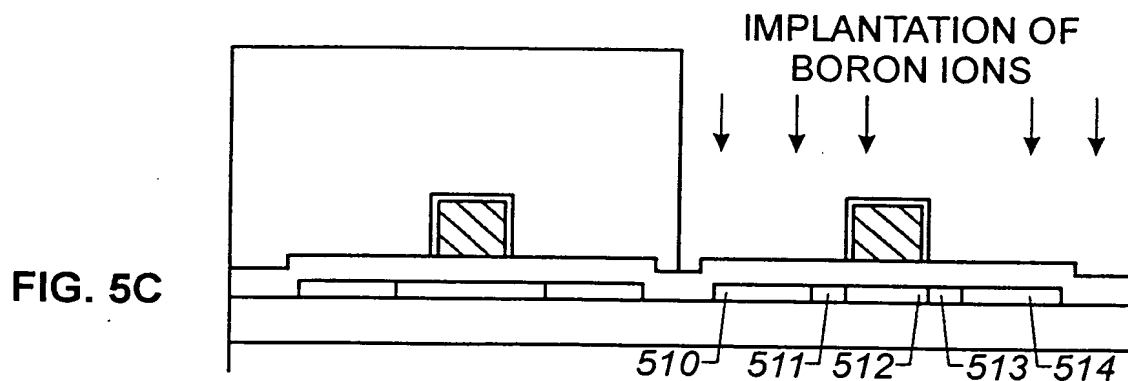
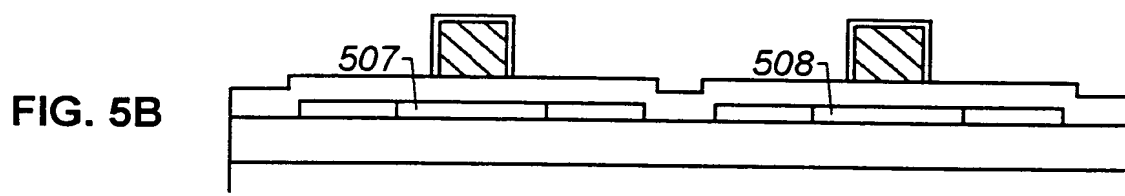
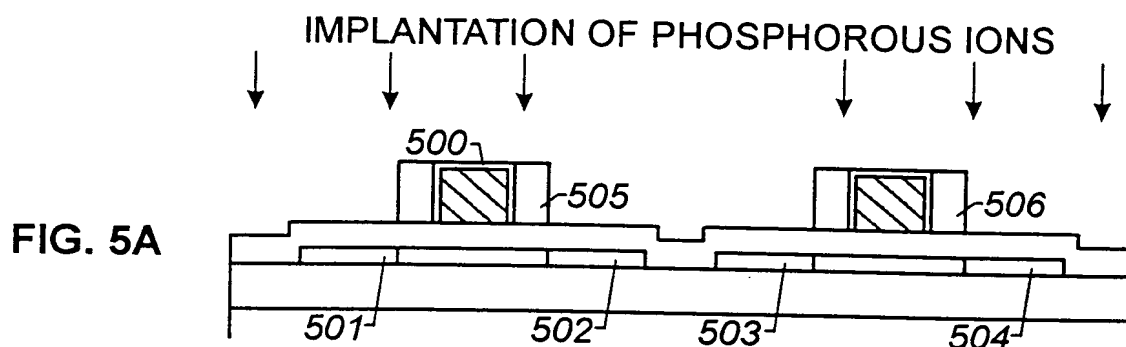


FIG. 6A

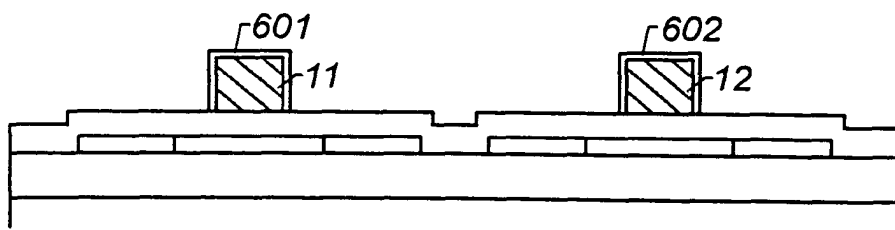


FIG. 6B

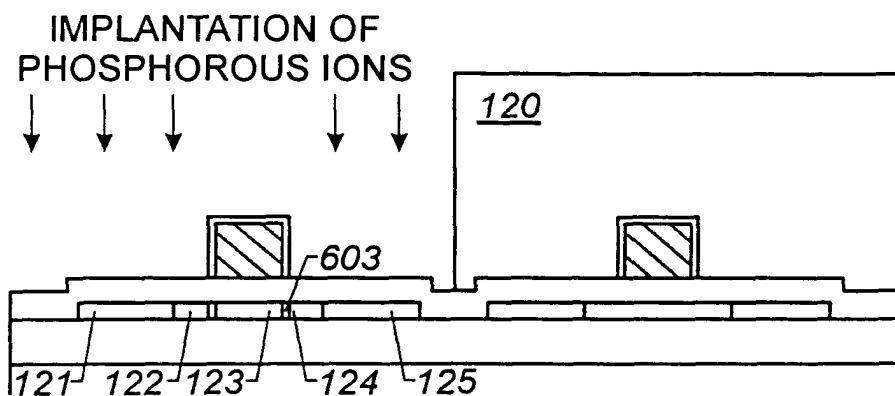


FIG. 6C

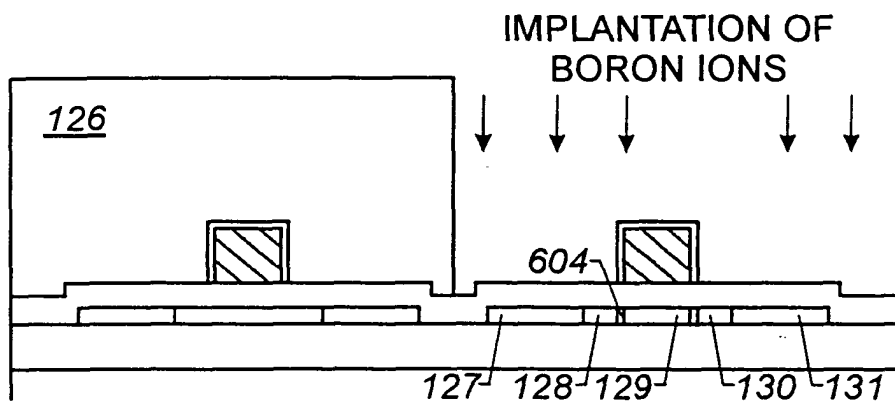
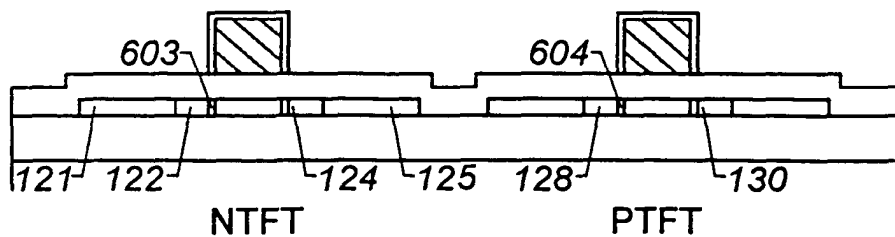


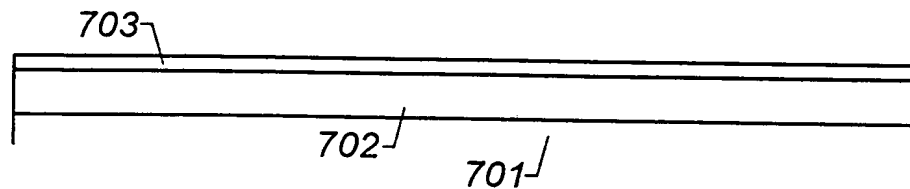
FIG. 6D



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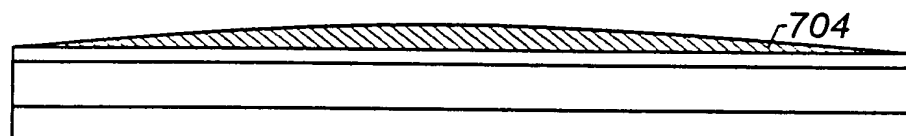
FORMATION OF AMORPHOUS SILICON FILM

FIG. 7A



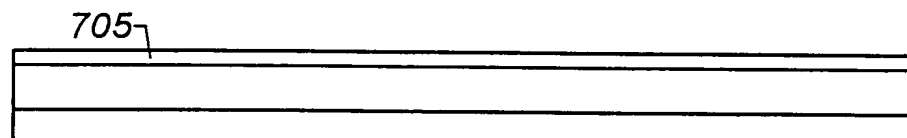
FORMATION OF WATER FILM
CONTAINING NICKEL SALT

FIG. 7B



HEATING PROCESS FOR CRYSTALIZATION

FIG. 7C



HEATING PROCESS IN ATMOSPHERE
CONTAINING HALOGEN ELEMENT

FIG. 7D

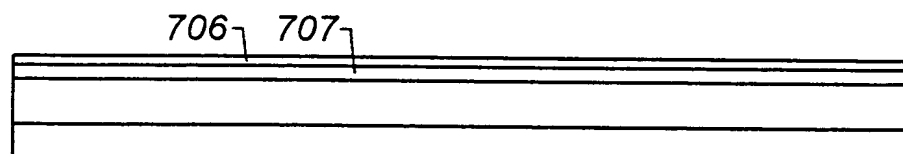


FIG. 7E

